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QUERY CONTROL FORM			RTIS USE ONLY
Application No. 10/047,550	Prepared by	BZM	Tracking Number 05931458
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a. Serial No.	f. Foreign Priority	k. Print Claim(s)	(P.) PTO-1449			
b. Applicant(s)	g. Disclaimer	I. Print Fig.	q. PTOL-85b			
c. Continuing Data	h. Microfiche Appendix	m. Searched Column	r. Abstract			
d. PCT	i. Title	n. PTO-270/328	s. Sheets/Figs			
e. Domestic Priority	j. Claims Allowed	o. PTO-892	t. Other			

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Attorney Docket No: SLM-06100

1 2	6.	(original) The method of claim 2, wherein the conductive layer further comprises a metal deposited onto the conductive polymer.
1	7.	(currently amended) The method of claim 1, wherein the selected portions of the
2		conductive layer on the top surface of the Ferroelectric ferroelectric material are selected
3		by patterning the conductive layer on the top surface of the Ferroelectric ferroelectric
4		material.
1	8.	(currently amended) The method of claim 7, wherein the conductive layer on the top
2		surface of the Ferroelectric ferroelectric material is patterned by:
3		a. forming a mask over the conductive layer on the top surface of the Ferroelectric
4		ferroelectric material;
5		b. selectively removing the exposed portion of the conductive layer on the top
6		surface of the Ferroelectric ferroelectric material; and
7		c. removing the mask.
1	9.	(original) The method of claim 8, wherein the mask is formed from a photo-resist.
1	10.	(currently amended) The method of claim 9, wherein the mask is formed by:
2		a. depositing the photo-resist on the conductive layer on the top surface of the
3		Ferroelectric ferroelectric material;
4		b. exposing areas of the photo-resist with a light source according to a predetermined
5		pattern; and
6		c. developing the photo-resist to remove the unexposed portions of the photo-resist.
1	11.	(currently amended) The method of claim 1, further comprising the steps of placing the
2		conductive layer on the top surface of the Ferroelectric ferroelectric material and the
3		conductive layer on the bottom surface of the Ferroelectric ferroelectric material in
4		electrical communication.
1	12.	(currently amended) The method of claim 11, wherein the step of placing the conductive

layer on the top surface of the Ferroelectric ferroelectric material and the conductive layer

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(37 CFR § 1.98(b))

Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

Applicants: Gregory D. Miller et al Filing Date: January 15, 2002

Group Art Unit; 2881- 1731

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			FOREIGN PATENTS	OR PUBLISHED FOREIGN PATENT APPLIC	ATIONS			
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CF	BF	0 627 644 A2	12/07/94	EP	G02B	27/00		x
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	FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS								
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